



Applicants: Wiesmann, et al.  
Serial No.: 10/622,843  
Filed: July 18, 2003  
Page 1 of 3

**PATENT**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants: Wiesmann, et al.

Serial No.: 10/622,843                                  Group Art Unit: 1763  
Filed: July 18, 2003                                      Confirmation No. 4758  
For: FLUORINATED PRECURSORS OF SUPERCONDUCTING  
    CERAMICS, AND METHODS OF MAKING THE SAME

Mail Stop DD  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**INFORMATION DISCLOSURE STATEMENT**

Sir:

In order to fulfill the requirements of candor and good faith set forth in 37 C.F.R. § 1.56, Applicants submit herewith the following disclosure in accordance with the provisions of 37 C.F.R. § 1.97 and § 1.98.

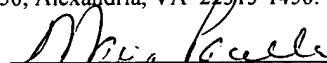
**I. UNITED STATES PATENTS**

| <b><u>PATENT NUMBER</u></b> | <b><u>ISSUE DATE</u></b> | <b><u>PATENTEE</u></b> |
|-----------------------------|--------------------------|------------------------|
| 5,231,074                   | July 27, 1993            | Cima et al.            |

**CERTIFICATE OF MAILING (37 CFR 1.8a)**

I hereby certify that this paper (along with any papers referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to: Mail Stop DD, Commissioner of Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

11/20/03  
Date

  
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Maria Pacella, Office of Intellectual Property and Sponsored Research

Applicants: Wiesmann, et al.  
Serial No.: 10/622,843  
Filed: July 18, 2003  
Page 2 of 3

## II. OTHER DOCUMENTS

1. **Author:** Chan et al.; **Title:** "Effect of the Post-Deposition Processing Ambient on the Preparation of Superconducting  $\text{YBa}_2\text{Cu}_3\text{O}_{7-x}$  Coevaporated Thin Films Using a  $\text{BaF}_2$  Source;" **Publication:** *Appl. Phys. Lett.* 53(15): 1443-1445; **Date of Publication:** October 1988.
2. **Author:** Solovyov et al.; **Title:** "*Ex-situ* Post-deposition Processing for Large Area  $\text{YBa}_2\text{Cu}_3\text{O}_7$  Films and Coated Tapes;" **Publication:** *IEEE Transactions on Applied Superconductivity* 11(1):2939-2942; **Date of Publication:** March 2001.
3. **Author:** Solovyov et al.; **Title:** "Thick  $\text{YBa}_2\text{Cu}_3\text{O}_7$  Films by Post Annealing of the Precursor by High Rate E-beam Deposition on  $\text{SrTiO}_3$  Substrates;" *Physica C.* 309: 269-274; **Date of Publication:** December 1998.
4. **Author:** Solovyov et al.; **Title:** "High Rate Deposition of 5 Micron Thick  $\text{YBa}_2\text{Cu}_3\text{O}_7$  Films using the  $\text{BaF}_2$  Ex-Situ Post Annealing Process;" **Publication:** *IEEE Transactions on Applied Superconductivity* 9(2):1467-1470; **Date of Publication:** June 1999.
5. **Author:** Solovyov et al.; **Title:** "Growth rate limiting mechanisms of  $\text{YBa}_2\text{Cu}_3\text{O}_7$  films manufactured by ex situ processing;" **Publication:** *Physica C.* 353:14-22; **Date of Publication:** 2001.
6. U.S. Application Publication No. 2003/0050195.

The above references are also listed on the accompanying Form PTO-1449. The Examiner is respectfully requested to consider these references in their entireties, and to indicate that he or she has done so by initialing the enclosed Form PTO-1449.

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If the Examiner has any questions or comments relating to the present application, he or she is respectfully invited to contact Applicants' attorney at the phone number set forth below.

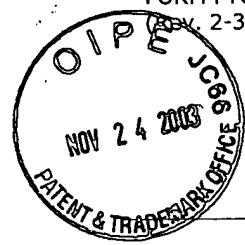
Respectfully submitted,



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Date: 11/17/2003

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|---|--|-------------------------------|--------------------------|
| FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE<br>(Rev. 2-32) PATENT AND TRADEMARK OFFICE      |  | ATTY. DOCKET NO.<br>BSA 03-01 | SERIAL NO.<br>10/622,843 |
| INFORMATION DISCLOSURE<br>STATEMENT BY APPLICANT<br><br>(Use several sheets if necessary) |  | APPLICANT<br>Wiesmann, et al. | CONFIRMATION NO.<br>4758 |
|   |  | FILING DATE<br>July 18, 2003  | GROUP<br>1763            |

## U.S. PATENT DOCUMENTS

| EXAMINER INITIAL |  | DOCUMENT NUMBER | DATE          | NAME        | CLASS | SUB CLASS | FILING DATE IF APPROPRIATE |
|------------------|--|-----------------|---------------|-------------|-------|-----------|----------------------------|
|                  |  | 5,231,074       | July 27, 1993 | Cima et al. |       |           |                            |

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

|  |  |  |
|--|--|--|
|  |  | 1. Author: Chan et al.; Title: "Effect of the Post-Deposition Processing Ambient on the Preparation of Superconducting $\text{YBa}_2\text{Cu}_3\text{O}_{7-x}$ Coevaporated Thin Films Using a $\text{BaF}_2$ Source;" Publication: <i>Appl. Phys. Lett.</i> 53(15): 1443-1445; Date of Publication: October 1988. |
|  |  | 2. Author: Solovyov et al.; Title: " <i>Ex-situ</i> Post-deposition Processing for Large Area $\text{YBa}_2\text{Cu}_3\text{O}_7$ Films and Coated Tapes;" Publication: <i>IEEE Transactions on Applied Superconductivity</i> 11(1):2939-2942; Date of Publication: March 2001.                                    |
|  |  | 3. Author: Solovyov et al.; Title: "Thick $\text{YBa}_2\text{Cu}_3\text{O}_7$ Films by Post Annealing of the Precursor by High Rate E-beam Deposition on $\text{SrTiO}_3$ Substrates;" <i>Physica C</i> . 309: 269-274; Date of Publication: December 1998.  |
|  |  | 4. Author: Solovyov et al.; Title: "High Rate Deposition of 5 Micron Thick $\text{YBa}_2\text{Cu}_3\text{O}_7$ Films using the $\text{BaF}_2$ Ex-Situ Post Annealing Process;" Publication: <i>IEEE Transactions on Applied Superconductivity</i> 9(2):1467-1470; Date of Publication: June 1999.                  |
|  |  | 5. Author: Solovyov et al.; Title: "Growth rate limiting mechanisms of $\text{YBa}_2\text{Cu}_3\text{O}_7$ films manufactured by ex situ processing;" Publication: <i>Physica C</i> . 353:14-22; Date of Publication: 2001.  |
|  |  | 6. U.S. Application Publication No. 2003/0050195.  |

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication with applicant.